

500.41374CX1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): S. KANNO, et al  
Serial No.: (not yet assigned)  
Filed: September 10, 2003  
For: WAFER STAGE FOR WAFER PROCESSING APPARATUS  
AND WAFER PROCESSING METHOD

**INFORMATION DISCLOSURE STATEMENT**  
**UNDER 37 CFR 1.97 & 1.98**

Mail Stop DD  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 10, 2003

Sir:

In the matter of the above-identified application, this information disclosure statement is being submitted with the following citation as specified in 37 CFR 1.97(d).

"A copy of any patent, publication or other information listed in an information disclosure statement is not required to be provided if it was previously cited by or submitted to the Office in a prior application, provided that the prior application is properly identified in the statement and relied upon for an earlier filing date under 35 U.S.C. 120."

Applicant(s) are submitting herewith a copy of Form PTO-1449 which list documents cited in parent application(s) Serial No. 10/087,747, filed March 5, 2002.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (500.41374CX1) and please credit any excess fees to such deposit account.

Respectfully submitted,

A handwritten signature in cursive script, appearing to read 'Melvin Kraus', written over a horizontal line.

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